

| INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449) | | | | ATTY. DOCKET NO. 005918 USA/FPS/MMCS/APC | | SERIAL NO. 09/943,955 RECEIVED DEC 19 2003 Technology Center 2100 | |
|---|--|----------|------------------|--|----------|--|----|
| | | | | APPLICANT SHANMUGASUNDRAM et al. | | | |
| | | | | FILING DATE August 31, 2001 | | GROUP 2122 | |
| U.S. PATENT DOCUMENTS | | | | | | | |
| EXAMINER'S INITIALS | PATENT NO. | DATE | NAME | CLASS | SUBCLASS | FILING DATE | |
| L.T.M-E | 4,207,520 | 06/10/80 | Flora et al. | 324 | 238 | 04/06/78 | |
| L.T.M-E | 4,209,744 | 06/24/80 | Gerasimov et al. | 324 | 241 | 03/27/78 | |
| L.T.M-E | 4,609,870 | 09/02/86 | Lale et al. | 324 | 225 | 09/13/84 | |
| L.T.M-E | 4,755,753 | 07/05/88 | Chern | 324 | 237 | 07/23/86 | |
| L.T.M-E | 5,427,878 | 06/27/95 | Corliss | 430 | 30 | 05/16/94 | |
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| L.T.M-E | 6,077,412 | 06/20/00 | Ting et al. | 205 | 143 | 10/30/98 | |
| L.T.M-E | 6,271,670 | 08/07/01 | Caffey | 324 | 642 | 02/08/99 | |
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| L.T.M-E | 6,442,496 | 08/27/02 | Pasadyne et al. | 702 | 83 | 08/08/00 | |
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| L.T.M-E | 6,587,744 | 07/01/03 | Stoddard et al. | 700 | 121 | 06/20/00 | |
| FOREIGN PATENT DOCUMENTS | | | | | | | |
| EXAMINER'S INITIALS | PATENT NO. | DATE | COUNTRY | CLASS | SUBCLASS | Translation | |
| | | | | | | Yes | No |
| L.T.M-E | WO 01/11679 | 02/15/01 | WIPO | — | — | X | |
| L.T.M-E | WO 01/080306 | 10/25/01 | WIPO | — | — | X | |
| OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
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| L.T.M-E | 1999. "Contactless Bulk Resistivity/Sheet Resistance Measurement and Mapping Systems." www.Lehighton.com/fabtech1/index.html . | | | | | | |
| L.T.M-E | 2000. "Microsense II Capacitance Gaging System." www.adetech.com . | | | | | | |
| EXAMINER <i>Lynette T. Umrigar-Evanni</i> | | | | DATE CONSIDERED <i>5/2/2004</i> | | | |

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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| LJM-E | El Chemali, Chadi et al. July/August 2000. "Multizone uniformity control of a chemical mechanical polishing process utilizing a pre- and postmeasurement strategy." <i>J. Vac. Sci. Technol.</i> Volume 18, No. 4. pp. 1287 - 1296. | | | | | | |
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| LJM-E | "NanoMapper FA factory automation wafer nanotopography measurement." http://www.phase-shift.com/nanomapperfa.shtml . | | | | | | |
| EXAMINER Lynette J. Umeg-Evuni | | | | DATE CONSIDERED 5/2/2004 | | | |

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